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**INFORMATION DISCLOSURE STATEMENT**

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Applicant: Shunpei YAMAZAKI

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**U.S. PATENT DOCUMENTS**

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date (if appropriate)
<i>RLG</i>	5,923,962	7/13/99	Ohtani et al.	_____	_____	
<i>RLG</i>	5,643,826	7/1/97	Ohtani et al.	_____	_____	

**FOREIGN PATENT DOCUMENTS**

	Document Number	Date	Country	Class	Subclass	Translation Yes No
<i>RLG</i>	7-130652	5/19/95	Japan	_____	_____	Abstract
<i>RLG</i>	9-312260	12/2/97	Japan	_____	_____	Abstract
<i>RLG</i>	64-31466	2/1/89	Japan	_____	_____	Abstract
<i>RLG</i>	1-270310	10/27/89	Japan	_____	_____	Abstract
<i>RLG</i>	7-263697	10/13/95	Japan	_____	_____	Abstract
<i>RLG</i>	9-283439	10/31/97	Japan	_____	_____	Abstract
<i>RLG</i>	10-229201	8/25/98	Japan	_____	_____	Abstract

**OTHER DOCUMENTS** (Including Author, Title, Date, Pertinent Pages, Etc.)

	C.S. McCormick et al., "Low temperature fabrication of amorphous silicon thin film transistors by dc reactive magnetron sputtering", J. Vac. Sci. Technol. A 15(5), September/October 1997, pp. 2770-2776.

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